
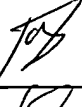
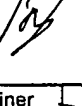



8/1/2003

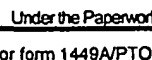
[illegible]

OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)	
	PETER SINGER, Editor-in Chief, August 1, 1999, "Dual-Damascene Challenges Dielectric Etch", http://www.e-insite.net/semiconductor/index.asp?layout=articlePrint&articleID=CA165320 , last visited 05/29/2003
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Sheet 2

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Complete if Known

Application Number 10/632,873

Filing Date 8/1/2003

First Named Inventor Kim, et al.

Art Unit 1765

Examiner Name

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NON PATENT LITERATURE DOCUMENTS

Examiner Initials *	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
	C1	European Search Report for Application 04018095.2-1235, 3/23/2005	
	C2	Morikawa Y, et al: "Control of Surface Reaction on Highly Accurate Low-K Methylsilsesquioxane Etching Process" Japanese Journal of Applied Physics. Tokyo, JP, vol. 42, no. 12A, Part 2, 1 December 2001 (2002-12-01), pages L1406-L1408, XP001164580 ISSN: 00221-4922, page L1407	

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